

1508.63671

PATENT

1c525 U.S. PTO
09/521389
03/08/00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application)
)
Applicant: Shigeru Okamoto)
)
Divisional of)
Serial No. 08/959,763)
)
Filed: October 29, 1997)
)
For: EMBEDDED ELECTRO-)
CONDUCTIVE LAYER)
AND METHOD FOR)
FORMATION THEREOF)
)
Art Unit: 2823)
)
Examiner: Eaton, K.)

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F-CLASS.WCM
Appr. February 20, 1998

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In accordance with 37 C.F.R. §§1.56, 1.97 and 1.98, Applicant through counsel
herewith submits copies of the publications as set forth in the attached form PTO-1449 as
follows:

U.S. DOCUMENTS

4,990,997	Nishida	Feb. 5, 1991
5,070,036	Stevens	Dec. 3, 1991
5,290,733	Hayasaka et al.	Mar. 1, 1994
5,464,666	Fine et al.	Nov. 7, 1995
5,489,548	Nishioka et al.	Feb. 6, 1996
5,552,341	Lee	Sep. 3, 1996
5,614,756	Forouhi et al.	Mar. 25, 1997
5,627,102	Shinriki et al.	May 6, 1997
5,641,985	Tamura et al.	Jun. 24, 1997
5,652,464	Liao et al.	Jul. 29, 1997
5,739,579	Chiang et al.	Apr. 14, 1998
5,793,057	Summerfelt	Aug. 11, 1998
5,801,095	Huang et al.	Sep. 1, 1998
5,801,098	Fiordalice et al.	Sep. 1, 1998
5,903,053	Lijima et al.	May 11, 1999

OTHER DOCUMENTS

John A.T. Norman, David A. Roberts et al., ENHANCED
DEPOSITION OF COPPER FILMS BY CVD - Advanced
Metalization for ULSI Application pp. 57-62

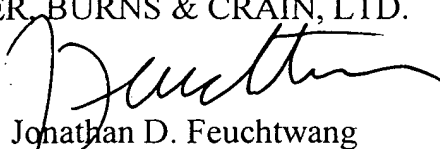
Susan L. Cohen, Michael Liehr and Srinandan Kasi,
Mechanisms of copper chemical vapor depositions, Appl.
Phys. Lett. 60 (1), January 6, 1992, pp. 50-52

Applicant respectfully requests that the Examiner consider the above-listed references in the examination of this application and list these references of record in the application.

Respectfully submitted

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